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Application No.: 10/603,924

**APR - 4 2006**

Docket No.: JCLA7109

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Examiner: NGUYEN, THANH T

Group Art Unit: 2813

In re PATENT APPLICATION of

Applicants : Shao-Chung Hu )

Serial No. : 10 / 603,924 )

Filed : June 24, 2003 )

For : POST-CMP REMOVAL OF SURFACE )  
CONTAMINANTS FROM SILICON WAFER )**AMENDMENT****AMENDMENT AFTER FINAL**

**Mail Stop AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

The Office Action mailed December 5<sup>th</sup>, 2005 has been carefully considered. In response thereto, please enter the following amendments and consider the following remarks.